

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re New National Phase Patent Application of )  
Shinji MAEKAWA et al. )  
International Application No. PCT/JP2004/016181 )Attn: US/DO/EO  
International Filing Date: October 25, 2004 )  
For: METHOD FOR FORMING WIRING, METHOD )  
FOR MANUFACTURING THIN FILM TRANSISTOR )  
OR AND DROPLET DISCHARGING METHOD )Date: April 12, 2006

PRELIMINARY AMENDMENT

United States Patent and Trademark Office  
Customer Service Window  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314

Sir:

Please preliminarily amend the subject application as follows: